

China

OPTO-EDU

CE, Rohs

A62.4510

5~20 Days

5000 pcs/ Month

1pc

Opto Edu A62.4510 Electron Probe Microscope , Spm Microscope Usb

FOB \$1~1000, Depend on Order Quantity

Carton Packing, For Export Transportation

Basic Information

- Place of Origin:
- Brand Name:
- Certification:
- Model Number:
- Minimum Order Quantity:
- Price:
- Packaging Details:
- Delivery Time:
- Payment Terms: L/C, T/T, Western Union
- Supply Ability:



0

Product Specification

• Work Mode:	"Contact Mode Tapping Mode Optional Friction Mode Phase Mode Magnetic Mode Electrostatic Mode"
Current Spectrum Curve:	"RMS-Z Curve F-Z Force Curve"
• XY Scan Mode:	"Probe Driven Scanning, Piezo Tube Scanner"
• XY Scan Range:	70×70um
• XY Scan Resolution:	0.2nm
Z Scan Range:	5um
Z Scan Resolution:	0.05nm
Scan Speed:	0.6Hz~30Hz
Scan Angle:	0~360°
Sample Weight:	≤15Kg
Stage Size:	"Dia.100mm Optional Dia.200mm Dia.300mm"
Stage XY Moving:	" 100x100mm, Resolution 1um Optional

Probe Scanning Atomic Force Microscope

Gantry scanning head design, marble base, vacuum adsorption stage, sample size and weight are basically unlimited Intelligent needle feeding method with automatic detection of motor-controlled piezoelectric ceramics to protect probes and samples Automatic optical positioning, no need to adjust focus, real-time observation and positioning probe sample scanning area Equipped with closed metal shield, pneumatic shock-absorbing table, strong anti-interference ability; Integrated scanner nonlinear correction user editor, nanometer characterization and measurement accuracy is better than 98%



A62.4510 Probe Scanning Atomic Force Microscope (AFM)





Product Details

- The first commercial atomic force microscope in China that keeps the sample stationary and the probe moves and scans;
- The sample size and weight are almost unlimited, especially suitable for the detection of very large samples;
- The sample stage is highly expandable, which is very convenient for multi-instrument combination to realize in-situ detection;
- Electric control of sample moving table and lifting table, which can be programmed with multi-point position to realize fast automatic detection;
- Gantry scanning head design, marble base, vacuum adsorption and magnetic adsorption stage;
- The motor automatically controls the intelligent needle feeding method of the piezoelectric ceramic automatic detection to protect the probe and the sample;
- + High magnification auxiliary optical microscope positioning, real-time observation and positioning of probe and sample scanning area;
- Integrated scanner nonlinear correction user editor, nanometer characterization and measurement accuracy better than 98%.

Application Case



latter in the incident of the latter in the



1D raster/scan range 50 μ mimes50 μ m

Specification



	A62.4510		A62.4511			
	Contact Mode		Contact Mode			
	Tapping Mode		Tapping Mode			
Nork Mode	Optional		Optional			
NOIR MODE	Friction Mode		Friction Mode			
	Phase Mode		Phase Mode	Phase Mode		
	Magnetic Mode		Magnetic Mode			
	Electrostatic Mode		Electrostatic Mo	ode		
Current Spectrum Curve	RMS-Z Curve		RMS-Z Curve			
	F-Z Force Curve		F-Z Force Curv	e		
(Y Scan Mode	Probe Driven Scanning,		Sample Driven	Scanning, Closed Loop		
	Piezo Tube Scanner		Piezoelectric Sł	nift Scanning Stage		
(Y Scan Range	70×70um		Closed Loop 10	00×100um		
KY Scan Resolution	0.2nm		Closed Loop 0.	5nm		
Z Scan Mode			Probe Driven S	canning		
Scan Bange	5um		5um			
Z Scan Resolution	0.05pm		0.05nm			
scan Speed	0.6HZ~30HZ		0.6HZ~30HZ			
Scan Angle	0~360°		0~360°			
Sample Weight	≤15Kg		≤0.5Kg			
	Dia.100mm		Dia.100mm			
Stage Size	Optional		Optional			
	Dia.200mm		Dia.200mm			
	Dia.300mm		Dia.300mm	Dia.300mm		
	100x100mm, Resolution 1um	1	100x100mm, R	esolution 1um		
Ctopp VV Mauing	Ontional		Ontional			
Stage XY Moving	Optional					
	200x200mm		200x200mm			
	300x300mm		15mm Recolution 10mm			
	15mm, Resolution 10nm		Optional			
Stage Z Moving	Optional		20mm			
	20mm					
	25mm		25mm			
	Spring Suspension		Spring Suspens	sion		
Shock-Absorbing Design			Optional			
0 0	Optional		Optional			
	Active Shock Absorber		Active Shock A	Active Shock Absorber		
	Objective 5x		Objective 5x			
5.0M Digital Camera			5.0M Digital Ca	mera		
Optical System						
	Optional		Optional			
	Objective 10x		Objective 10x			
	Objective 20x		Objective 20x			
	USB2.0/3.0		USB2.0/3.0			
Output			Win XP/7/8/10			
Dutput Software	Win XP/7/8/10		Win XP/7/8/10			
Dutput Software Main Body	Win XP/7/8/10 Gantry Scan Head, Marble B	ase	Win XP/7/8/10 Gantry Scan He	ead, Marble Base		
Dutput Software Main Body	Win XP/7/8/10 Gantry Scan Head, Marble B	ase	Win XP/7/8/10 Gantry Scan He	ead, Marble Base		
Dutput Software Main Body Gicroscope	Win XP/7/8/10 Gantry Scan Head, Marble B Optical Microscope	ase Electron Micr	Win XP/7/8/10 Gantry Scan He oscope	ead, Marble Base		
Output Software Main Body Microscope Max Resolution (um)	Win XP/7/8/10 Gantry Scan Head, Marble B Optical Microscope 0.18	Electron Micro 0.00011	Win XP/7/8/10 Gantry Scan He oscope	ead, Marble Base Scanning Probe Microscope 0.00008		
Output Software Main Body Vicroscope Max Resolution (um)	Win XP/7/8/10 Gantry Scan Head, Marble B Optical Microscope 0.18	Electron Micro 0.00011	Win XP/7/8/10 Gantry Scan He oscope	ead, Marble Base Scanning Probe Microscope 0.00008 Imaging high-order graphitic		

Probe-Sample Interaction Measure Signal Information Force Electrostatic Force Shape Tunnel Current Current Shape Magnetic Force Phase Magnetic Structure Electrostatic Force Phase Shape Gonductivity Resolution Working Condition Working Temperation Damge to Sample SPM Atom Level 0.1nm Normal, Liquid, Room or Low None 1-2 Atom Level TEM Point 0.3-0.5nm High Vaccum Room Temperation Small Usually <100nm SEM 6-10nm High Vaccum Room Temperation Small Usually <100nm SEM 6-10nm High Vaccum Room Temperation Small 1um @10000x TIM Atom Level 0.1nm Super High Vaccum 30-80K Damge Atom Thickness System Diaphragm Force Control System For Force F						
Force Electrostatic Force Shape Tunnel Current Current Shape, Conductivity Magnetic Structure Phase Magnetic Structure Electrostatic Force Phase sharge distribution Resolution Working Condition Working Temperation more inspection Depth SPM Atom Level 0.1nm Normal, Liquid, Room or Low None 1-2 Atom Level SPM Atom Level 0.1nm Normal, Liquid, Room Temperation Small Usually <100nm SEM 6-10nm High Vaccum Room Temperation Small 1/0mm@10x SEM 6-10nm High Vaccum Room Temperation Small 1/0mm@10x SIM Atom Level 0.1nm Super High Vaccum 30-80K Damge Atom Thickness System Diaphragm Uput High Vaccum 30-80K Damge Atom Thickness System Diaphragm Uput High Vaccum 30-80K Damge Atom Thickness Uput High Vaccum 30-80K Damge Atom Thickness Uput High Vaccum 30-80K Damge<	Probe-Sample Interaction	Measure Signa	al	Information		
Bit Direct Interest Current Shape. Conductivity Magnetic Force Phase Magnetic Structure Electrostatic Force Phase charge distribution Resolution Working Condition Morking Temperation Damge to Sample Inspection Depth SPM Atom Level 0.1nm Normal, Liquid, Vacuum Room or Low Normal, Liquid, Temperation Normal, Liquid, Room or Low Normal, Liquid, Vacuum Room Temperation Small Usually <100nm SEM 6-10nm High Vaccum Room Temperation Small Usually <100nm SEM 6-10nm High Vaccum Room Temperation Small 10mm @10x IM Atom Level 0.1nm Super High Vaccum S0-80K Damge Atom Thickness System Diaphragm Image Control System Image Temperation Host Image Temperation Image Temperation Small Image Temperation Small Image Temperation Image Temperation Small Image Temperation Small Image Temperation Statice 0.1-0.2nm High Vaccum S0-80K Damge Atom Thickness Image Temperatio	Force	Electrostatic F	orce	Shape		
Alagnetic Force Phase Magnetic Structure Electrostatic Force Phase charge distribution Resolution Working Temperation Damge to Sample Inspection Depth SPM Atom Level 0.1nm Normal, Liquid, Room or Low None 1-2 Atom Level TEM Point 0.3-0.5nm Liquid, Room Temperation Small Usually <100nm SEM 6-10nm High Vaccum Room Temperation Small 10mm @10x SEM 6-10nm High Vaccum Room Temperation Small 10mm @10x SEM 6-10nm Super High Vaccum 30-80K Damge Atom Thickness System Diaphragm Host Fortion System Fortion Sys	Funnel Current	Current		Shape, Conductivity	/	
Electrostatic Force Phase phase phase phase distribution Resolution Working Condition Working Temperation Damge to Sample Inspection Depth SPM Atom Level 0.1nm Normal, Liquid, Meacum Room or Low None 1-2 Atom Level TEM Point 0.3-0.5nm High Vaccum Room Temperation Small Usually <100nm	Magnetic Force	Phase		Magnetic Structure		
Resolution Working Condition Working Temperation Damge to Sample Inspection Depth SPM Atom Level 0.1nm Normal, Liquid, Yacuum Room or Low Temperation None 1~2 Atom Level Point 0.3~0.5mm High Vaccum Room Temperation Small Usually <100nm	Electrostatic Force	Phase		charge distribution		
SPM Atom Level 0.1nm Normal, Liquid, Vacuum Room or Low Temperation None 1-2 Atom Level FEM Latice 0.1-0.2nm High Vaccum Room Temperation Small Usually <100nm SEM 6-10nm High Vaccum Room Temperation Small Usually <100nm SEM 6-10nm High Vaccum Room Temperation Small 10mm @10x TIM Atom Level 0.1nm Super High Vaccum 30-80K Damge Atom Thickness System Diaphragm Image: Control System PC Handwheel Rocker How Temperation Temperation Image: Control System Image: Temperation	Resolution	Working Condition	Working Temperation	Damge to Sample	Inspection Depth	1
Point 0.3-0.5nm Latice 0.1-0.2nm High Vaccum Room Temperation Small Usually <100nm SEM 6-10nm High Vaccum Room Temperation Small 10mm @10x tum @10000x FIM Atom Level 0.1nm Super High Vaccum 30-80K Damge Atom Thickness System Diaphragm Handwheel Rocker Handwheel Rocker Host Host Host PC Umm	SPM Atom Level 0.1nm	Normal, Liquid, Vacuum	Room or Low Temperation	None	1~2 Atom Level	
SEM 6-10nm High Vaccum Room Temperation Small 10mm @10x 1um @10000x FIM Atom Level 0.1nm Super High Vaccum 30-80K Damge Atom Thickness System Diaphragm Image Atom Thickness Opesktop PC Image Control System Image Host Image Image Image Image Image Opesktop Image <td colspa="4</td> <td>TEM Point 0.3~0.5nm Lattice 0.1~0.2nm</td> <td>High Vaccum</td> <td>Room Temperation</td> <td>Small</td> <td>Usually <100nm</td> <th></th>	TEM Point 0.3~0.5nm Lattice 0.1~0.2nm	High Vaccum	Room Temperation	Small	Usually <100nm	
Atom Level 0.1nm Super High Vaccum 30-80K Damge Atom Thickness System Diaphragm Handwheel Rocker Handwheel Rocker Host Host PC Image Image Image Image Image Image Image Image Image Image Image	SEM 6-10nm	High Vaccum	Room Temperation	Small	10mm @10x 1um @10000x	
System Diaphragm	FIM Atom Level 0.1nm	Super High Vaccum	30~80K	Damge	Atom Thickness	
	Desktop PC	AC reaches Control	System			

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